

503.34403VP2

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): MASUDA, et al

Serial No.: (not yet assigned)

Filed: October 20, 1999

For: PLASMA ETCHING APPARATUS AND PLASMA ETCHING
METHOD

Group:

Examiner:

INFORMATION DISCLOSURE STATEMENT
UNDER 37 CFR 1.97 & 1.98

Assistant Commissioner for Patents
Washington, D.C. 20231

October 20, 1999

Sir:

In the matter of the above-identified application,
this information disclosure statement is being submitted with
the following citation as specified in 37 CFR 1.97(d).

"A copy of any patent, publication or other
information listed in an information disclosure statement
is not required to be provided if it was previously cited
by or submitted to the Office in a prior application,
provided that the prior application is properly
identified in the statement and relied upon for an
earlier filing date under 35 U.S.C. 120."

Applicant(s) are submitting herewith a copy of Form PTO-
1449 which list documents cited in parent application(s)
Serial No. 09/227,332, which is a Continuation-in-Part of
Serial No. 08/611,758, now U.S. Patent No. 5,874,012.



It is respectfully requested that this information disclosure statement be considered by the Examiner.

Please charge any shortage in the fees due in connection with the filing of this paper, including extension of time fees, to Deposit Account No. 01-2135 (503.34403VP2) and please credit any excess fees to such deposit account.

Respectfully submitted,



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